Fabrication of CdS (n-type) and CdTe (p-type) Thin Film Semiconductor Materials via Electrodeposition

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Technologically, the electrodeposition (ED) method through the influence of potential, temperature, pH and composition of the reactants offers an excellent control over the properties of semiconductors. Using a potentiostatic approach, the thin films of CdS and CdTe were deposited on glass/ITO or glass/FTO substrates. CdS thin films were deposited in baths of cadmium chloride and ammonium thiosulphate at pH 1.40 at room temperature (28 - 30 °C) at the growth voltages ranging from -700 mV to -1500 mV (Best at -1100 mV), with respect to standard Ag/AgCl electrode. CdTe thin films were deposited in a bath of cadmium sulphate, cadmium chloride, and tellurium dioxide at pH 2.00 at 85 °C at -1570 mV growth voltage with respect to standard Ag/AgCl electrode. Resulted films were characterized by XRD for the determination of the bulk structure, Optical absorption for band gap energy measurements, photoelectrochemical cell

(PEC) measurement and I-V characteristics for the determination of conductivity type of the thin films. ED-CdS was found to be n-type belonging to hexagonal crystal system with the highest V_{oc} value of -148.0 mV and J_{sc} value of 314.5 μA cm⁻² with respect to photoelectrochemical cell measurements made with 0.1 mol dm⁻³ Na₂S₂O₃. Band gap of ED-CdS was 2.54 eV. ED-CdTe was found to be p-type with the highest V_{oc} value of +56.8 mV and J_{sc} value of 35.8 μA cm⁻² with respect to photo-electrochemical cell measurements made with 0.1 mol dm⁻³ redox couple. Band gap of ED-CdTe. was 1.73 eV.

Keywords: Electrodeposition(ED), Potentiostatic approach, XRD, Optical absorption. Photoelectrochemical cell(PEC), I-V characteristics, Open circuit voltage (V_{oc}), Short circuit current density (J_{sc}), Band gap energy